

Title (en)

RESISTIVE CANTILEVER SPRING FOR PROBE MICROSCOPY

Title (de)

RESISTIVE CANTILEVERFEDER FÜR SONDENMIKROSKOPIE

Title (fr)

RESSORT EN PORTE-A-FAUX RESISTIF POUR LA MICROSCOPIE PAR SONDE

Publication

EP 1609164 A4 20101103 (EN)

Application

EP 03708379 A 20030313

Priority

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- GB 0302523 A 20030204
- EP 03250876 A 20030213

Abstract (en)

[origin: WO2004070765A1] I A dual- and triple- mode cantilever (10) suitable for simultaneously measuring both normal "adhesion" and lateral "friction" forces independently in three orthogonal directions. The cantilever design allows the measurements to be performed at high sensitivity. The cantilever is useful in Scanning Probe Microscopes "SPM's" and other force-measuring devices, such as the Atomic Force Microscope "AFM", the Friction Force Microscope "FFM", and in probe attachments for the Surface Forces Apparatus "SFA" where both normal and lateral forces acting on a tip need to be accurately and unambiguously measured. The cantilever structure may be used for both resistive and optical detection of tip (13) deflections.

IPC 1-7

H01J 37/00

IPC 8 full level

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CPC (source: EP)

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Citation (search report)

- [X] US 5959200 A 19990928 - CHUI BENJAMIN W [US], et al
- [X] US 2001028033 A1 20011011 - SHIMIZU NOBUHIRO [JP], et al
- [XA] EP 0869329 A2 19981007 - CANON KK [JP]
- See references of WO 2004070765A1

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